



Prof. Kyongnam Kim

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Professor Kyongnam Kim currently works in the Department of Semiconductor Engineering at Daejeon University, Republic of Korea. He received his Ph.D. in Materials Science and Engineering from Sungkyunkwan University in 2007, focusing on plasma sources and processes for large-area displays, and subsequently conducted postdoctoral research in Nuclear Engineering at the University of Illinois at Urbana-Champaign. His research interests include atomic layer etching (ALE) equipment, alternative gases and processes for carbon neutrality, cryogenic etching technologies, and sensor-based diagnostics for semiconductor equipment. At this conference, he will present on *"Development of an Endpoint Evaluation Sensor to Enhance Uniformity in Plasma Chamber Cleaning."*